TSMC-01-1440C

May 11, 2004

To: Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: Serial No. 10/822,197 04/09/04

Kuo-Chi Tu et al.

METHOD OF FABRICATING AN EMBEDDED DRAM FOR METAL-INSULATOR-METAL (MIM) CAPACITOR STRUCTURE

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation In An Application.

The following Patents and/or Publications are submitted to comply with the duty of disclosure under CFR 1.97-1.99 and 37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on May 17, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date 5/17/04

U.S. Patent 6,211,061 to Chen et al., "Dual Damascene Process for Carbon-Based Low-K Materials," teaches a dual damascene process with carbon-based low-k materials.

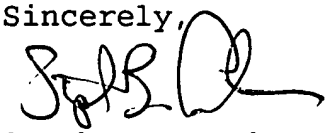
The following three U.S. Patents discuss MIM capacitor processes:

1) U.S. Patent 6,096,597 to Tsue et al., "Method for Fabricating an Integrated Circuit Structure."

2) U.S. Patent 6,329,234 to Ma et al., "Copper Process Compatible CMOS Metal-Insulator-Metal Capacitor Structure and Its Process Flow."

3) U.S. Patent 6,271,084 to Tu et al., "Method of Fabricating a Metal-Insulator-Metal (MIM) Capacitor Structure Using a Damascene Process."

Sincerely,



Stephen B. Ackerman,
Reg. No. 37761

Form PTO-1449

OTPE JC37 MAY 19 2004 PATENT & TRADEMARK OFFICE

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)	Application Number
TSMC-01-1440C	10/822,197
Applicant	
Kuo-Chi Tu et al.	
Filing Date	**Group Art Unit**
04/09/04	

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	6211061	4/3/01	Chen et al.	438	622	10/29/99
	6096597	8/1/00	Tsu et al.	438	240	1/28/98
	6329234	12/11/01	Ma et al.	438	210	7/24/00
	6271084	8/7/01	Tu et al.	438	253	1/16/01

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES	Translation NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER	DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.